

This instruction covers the set-up and safe use of the KLA-Tencor P10 Stylus Profiler. This machine is a stylus contact profiler capable of 150mm scan lengths with  $\sim 10\text{\AA}$  resolution and  $\sim 20\text{\AA}$  noise floor. It is capable of measuring step height, roughness, and waviness on samples with a firm surface.

## 1. SAFETY REQUIREMENTS

- 1.1. Eye protection must be worn whenever in the Soft Materials Lab, except when using a microscope or when wearing protective goggles.
- 1.2. Information regarding the hazardous materials used in this lab may be found through SDS documentation located on the Wiki.
- 1.3. Operate the P10 Stylus Profiler with all protective shields and doors in place.
- 1.4. Do not reach into the tool except to place your sample on the chuck. Do not put your hands under the scan head, or you may damage the stylus.

## 2. EQUIPMENT

- 2.1. KLA-Tencor P10 Stylus Profiler
  - 2.1.1. Manufacturer: KLA-Tencor, Model: P-10, S/N: 0701114362
  - 2.1.2. Computer, keyboard and monitor
  - 2.1.3. Isolation table
  - 2.1.4. VLSI Standards;
    - 2.1.4.1. VLSI Step Height Standard,  $8.00\ \mu\text{m}$
    - 2.1.4.2. VLSI Step Height Standard,  $9400\text{\AA}$  (85nm)

## 3. TOOL CONFIGURATION

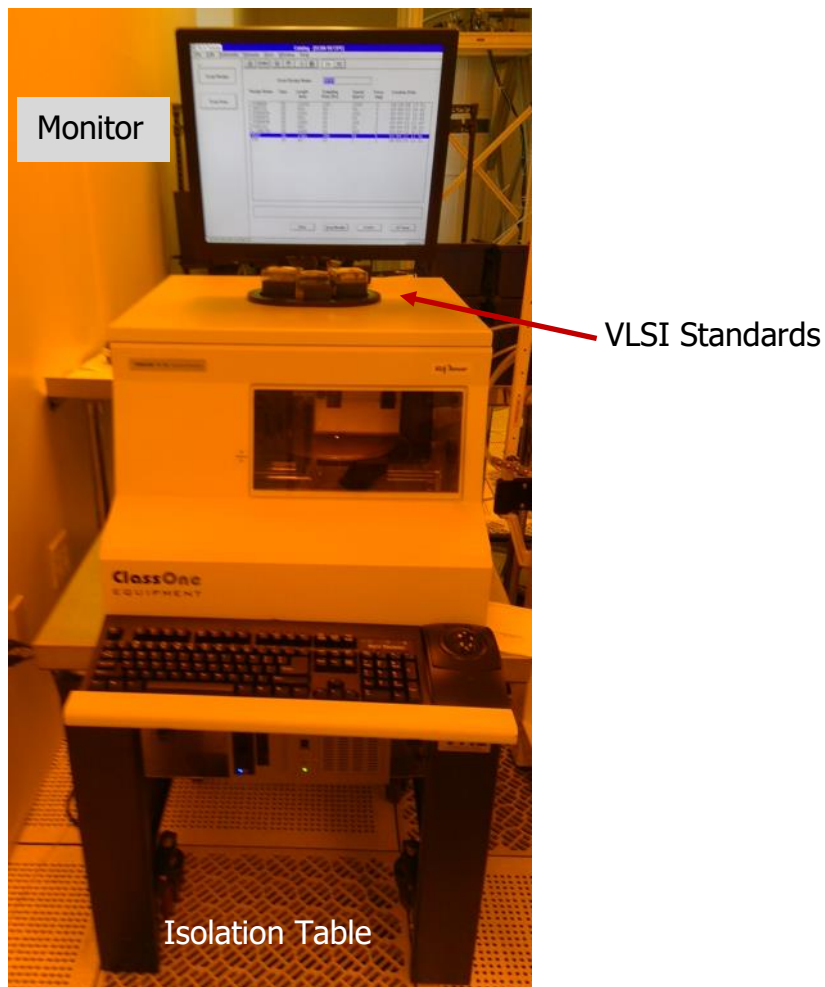
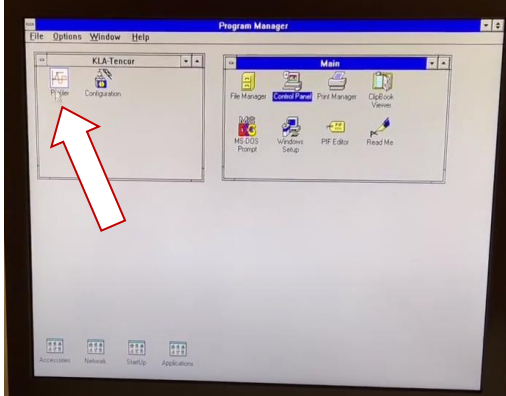


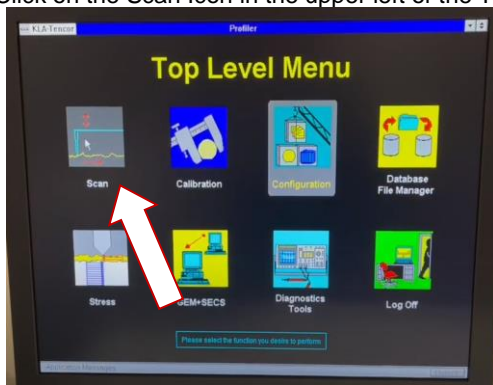
Figure 1

4. CYCLE OF OPERATION

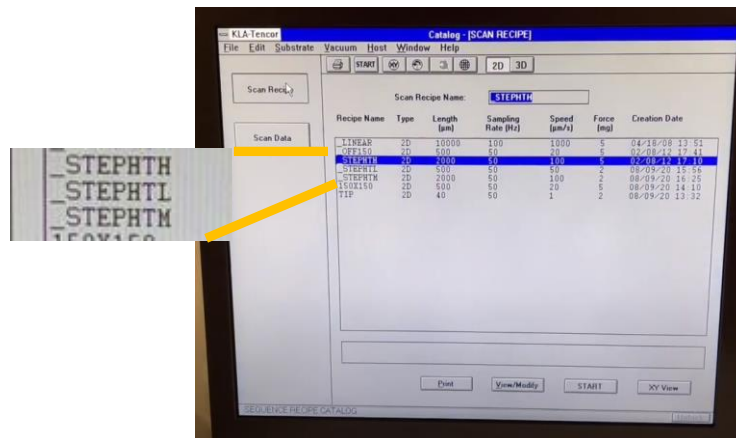
- 4.1. Enable the tool in iLab
- 4.2. Double click the Profiler icon if not already open



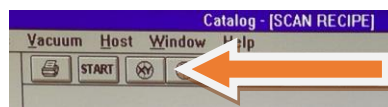
- 4.3. Click on the Scan Icon in the upper left of the Top Level Menu page



- 4.4. Choose an existing recipe by placing the cursor over the recipe and double left click (\_STEPHTH; 327µm or less, \_STEPHTM; 65µm or less, \_STEPHTL; 13µm or less). The recipe selection will depend on the size of the sample step to be measured.


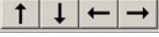


- 4.5. Press XY button to switch to camera mode
- 4.6. Press the MAN LOAD button which will cause the stage to move toward the front of the tool.
- 4.7. After the stage movement stops, open the door



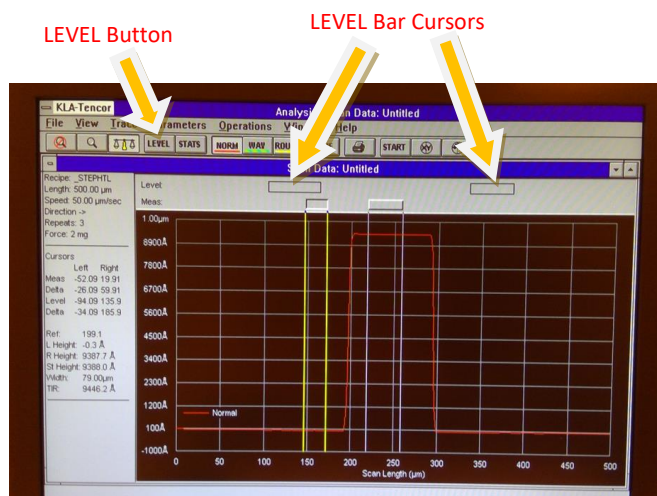
FOR BASELINE MEASUREMENT

- 4.8. Load the VLSI standard sample with extreme care placing it in the **exact center** of the chuck covering all 5 vacuum ports. *Note: Keep your hand away from the stylus head to avoid damage to the instrument.*

- 4.9. Turn on the vacuum switch on the left side of door opening to prevent the sample from moving  
*Note: Small samples that do not cover all 5 vacuum ports require the exposed vacuum ports be covered with small pieces of silicon or glass OR the sample can be mounted to a larger carrier*
- 4.10. Close the door
- 4.11. Press the **MAN LOAD** again to move the chuck into the measurement position
- 4.12. Verify the sample is in the center of the stage and under the stylus
- 4.13. Press the FOCUS  this will move the stylus head down to the surface of the sample  
NOTE: Pressing the spacebar will stop the movement of the measurement assembly
- 4.14. Use the arrows  or click on the image to position the sample for measurement
- 4.15. Click and drag (from left to right) to define the stylus scan path. The path will be indicated by a blue line with an arrow indicating the scan direction.
- 4.16. Press OK when complete
- 4.17. Refer to Section 5 of this document if the scan parameters need be adjusted
- 4.18. Press the START button at the top of the menu bar

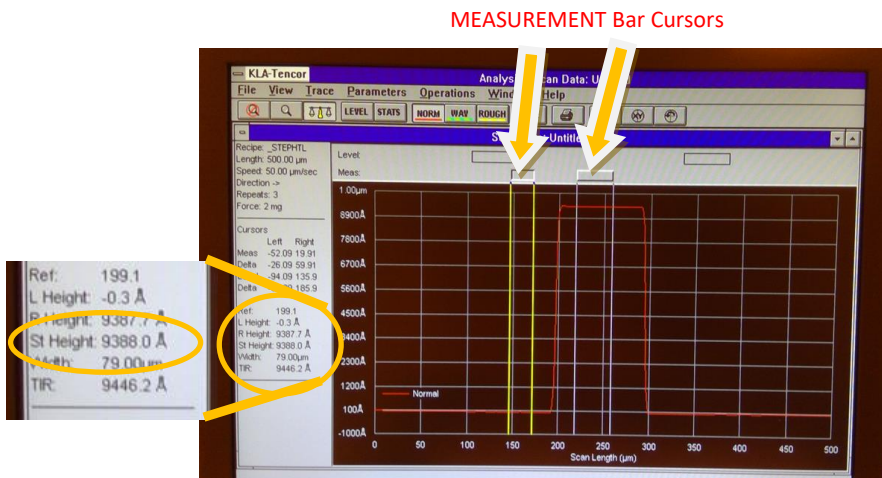
**LEVELING**

- 4.19. Once the scan is finished, press the LEVEL button at the top menu bar (shown below)
- 4.20. Drag, pull and manipulate the left and right Level bar cursors on the same plane to define a flat and even plane
- 4.21. Press the LEVEL button a second time to planarize the scan results



**STEP MEASUREMENT**

- 4.22. Position the left and right Measurement cursors to define the differential step. The width of the cursor bars can be adjusted.
- 4.23. Record the difference in height between the two cursors displayed next to St Height



- 4.24. If another measurement location is to be measured, press the XY button to move the sample and redefine the scan path.
- 4.25. When finished, press the XY button
- 4.26. Press the **MAN LOAD** button which will cause the stage to move toward the front of the tool
- 4.27. After the stage movement stops, open the door

- 4.28. Turn off the vacuum switch
- 4.29. Carefully remove your sample from the stage
- 4.30. Close the door
- 4.31. Press the **MAN LOAD** button which will cause the stage to move toward the home position
- 4.32. Exit the software and log out of iLab

**5. SUPPLEMENTAL DATA (Edit Recipes and Performance Specifications)**

EDITING RECIPES

- 5.1. Review and configure the scan parameters
  - 5.1.1. Scan Length = represented by the *blue arrow length*
  - 5.1.2. Scan Speed ( $\mu\text{m/s}$ )
  - 5.1.3. Sampling Rate (*amount of data collected*)
  - 5.1.4. Scan Direction (*Always scan left to right*)
  - 5.1.5. Applied Force (*Use 1 mg force for soft metals or polymers & use 2 mg force for metals and semiconductors*)
  - 5.1.6. Range/Resolution (*Ensure the step height maximum of the feature on interest is within this range*)
- 5.2. For short scans, 2mm and smaller, the general rule of thumb is to keep the scan time between 5 and 10 seconds
- 5.3. The General Parameters tab, and the Roughness Waviness tab may be used to determine slope, area, roughness, and other parameters from your scan analysis.
- 5.4. The MicroHead V SR (standard range) has a vertical range of 300  $\mu\text{m}$ , and is capable of scanning at forces between 0.5 and 5 mg
- 5.5. The BNC unit has a 2  $\mu\text{m}$  radius tip with a 60° angle installed and ask that all users limit the maximum force to 2mg
- 5.6. The motorized theta stage is controlled with the rotating arrow buttons on the XY screen.

PERFORMANCE SPECIFICATIONS

- 5.7. The P10 Stylus profiler at Purdue is equipped with the standard head configuration capable of 150mm scan lengths
- 5.8. Resolution is approximately 10 angstroms and a 20 angstroms noise floor
- 5.9. The software controlled motorized stage rides on a 12-inch optical flat
- 5.10. Vertical range 0  $\mu\text{m}$  to 300 $\mu\text{m}$
- 5.11. Substrate size from 3mmX3mm up to 200mm diameter
- 5.12. 2  $\mu\text{m}$  radius diamond stylus with 60° cone angle tip
- 5.13. Sample Surface Limitations
  - 5.13.1. No uncured SU8
  - 5.13.2. No uncured PDMS
  - 5.13.3. No uncured photoresists
  - 5.13.4. No other soft materials that might stick to the stylus

**6. STARTUP and SHUTDOWN**

STARTUP

- 6.1. Verify the tool is enabled in iLab
- 6.2. Verify the computer is powered on
- 6.3. Open the KLA-Tencor software if it is not running (shown in line 4.2)
- 6.4. Double click on the Profiler icon

SHUTDOWN

- 6.5. Verify the sample has been removed from the stage and the stage is in the home position
- 6.6. Exit out of the software
- 6.7. Disable the tool in iLab

**REVISION RECORD**

Reason for Revision	Date of Revision	Person Responsible
Initial Release	Apr 2022	Rich Harlan / Bill Rowe